

REPLY UNDER 37 CFR §1.116  
EXPEDITED PROCEDURE  
TECHNOLOGY CENTER 1700

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

<b>Applicant(s):</b> Chen, et al.	<b>Conf. No.:</b> 1057
<b>Serial No.:</b> 10/604,058	<b>Art. Unit:</b> 1763
<b>Filed:</b> 06/24/2003	<b>Examiner:</b> Ng, James Wai Heung
<b>Title:</b> PLASMA PROCESSING MATERIAL RECLAMATION AND REUSE	<b>Docket. No.:</b> FIS920030132US1 (IBMF-0018)

AF Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**AFTER-FINAL AMENDMENT**

Sir:

**I. INTRODUCTORY COMMENTS**

This paper is in response to the Final Office Action of 21 May 2007. Please amend the above-referenced patent application as follows:

**The Amendments to the Claims** are reflected in the listing of the claims that begins on page 2 of this paper.

**Remarks** begin on page 5 of this paper.